



RESPONSE UNDER 37 CFR 1.116
EXPEDITED PROCEDURE
EXAMINING GROUP 2125

00862.022199.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:)
Keiji EMOTO) : Examiner: P. L. Rodriguez
Application No.: 09/833,766) : Group Art Unit: 2125
Filed: April 13, 2001) : Confirmation No.: 4154
For: PIPE STRUCTURE, ALIGNMENT APPARATUS,) April 2, 2004
ELECTRON BEAM LITHOGRAPHY)
APPARATUS, EXPOSURE APPARATUS,)
EXPOSURE APPARATUS MAINTENANCE)
METHOD, SEMICONDUCTOR DEVICE)
MANUFACTURING METHOD, AND SEMI-)
CONDUCTOR MANUFACTURING FACTORY)

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APR 07 2004

Technology Center 2100

Mail Stop AF
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

LETTER TRANSMITTING CORRECTED FORMAL DRAWING

Sir:

Transmitted herewith is one (1) formal drawing sheet, Figure 12, to be substituted for the corresponding drawing sheet currently on file in the above-identified application.

Figure 12 incorporates the change requested by Applicants in a Request for Approval of Drawing Changes filed on November 19, 2003, which was subsequently approved by the Examiner in the Official Action dated February 5, 2004.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should continue to be directed to our address given below.

Respectfully submitted,



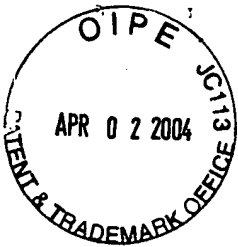
Attorney for Applicant

Lawrence A. Stahl

Registration No. 30,110

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SEW/LAS/eab/eyw

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In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS, ELECTRON
BEAM LITHOGRAPHY APPARATUS, EXPOSURE APPARATUS,
EXPOSURE APPARATUS MAINTENANCE METHOD, AND
SEMICONDUCTOR DEVICE MANUFACTURING METHOD, AND
SEMICONDUCTOR MANUFACTURING FACTORY

)
: Examiner: P. L. Rodriguez
)
: Group Art Unit: 2125
)
: Confirmation No.: 4154
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: April 2, 2004

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Sir:

Transmitted herewith is an Amendment After Final Rejection in the above-identified application.


☒ No additional fee is required.

The fee has been calculated as shown below:

CLAIMS AS AMENDED						
	CLAIMS REMAINING AFTER AMENDMENT		HIGHEST NO. PREVIOUSLY PAID FOR	PRESENT EXTRA	RATE	ADDITIONAL FEE
TOTAL CLAIMS	27	MINUS	27	= 0	x \$9 \$18	\$0.00
INDEP. CLAIMS	11	MINUS	11	= 0	x \$43 \$86	\$0.00
Fee for Multiple Dependent claims \$145/\$290						—
TOTAL ADDITIONAL FEE FOR THIS AMENDMENT						\$0.00

- ☐ °Verified Statement claiming small entity status is enclosed, if not filed previously.
- ☐ A check in the amount of \$_____ is enclosed including the additional claims fee.
- ☐ Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- ☒ Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- ☐ A check in the amount of \$_____ to cover the fee for a two month extension is enclosed.
- ☐ A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.
- ☒ Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicant
Lawrence A. Stahl
Registration No. 30,110

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